



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Robert J. Small and Xiaowei Shang
Assignee: EKC Technology, Inc.
Title: Chemical-Mechanical Planarization Using Ozone
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INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR § 1.97(b)

Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information listed herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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Respectfully submitted,

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